

### **Inventor Information**

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### **Correspondence Information**

Correspondence Customer Number:: 25944

### **Application Information**

Title Line One::	METHOD AND APPARATUS FOR ION
Title Line Two::	ATTACHMENT MASS SPECTROMETRY
Title Line Three::	
Title Line Four::	
Total Drawing Sheets::	9
Docket Number::	111522

### **Continuity Information**

>This application is a:: Division of  
Application One::  
Filing Date::  
Patent Number::  
which is a:: Division of  
>>Application Two::  
Filing Date::  
Patent Number::

#### **Prior Foreign Applications**

Foreign Application One:: JP 2000-401483  
Filing Date:: December 28, 2000  
Country:: Japan  
Priority Claimed:: Yes  
Foreign Application Two::  
Filing Date::  
Country::  
Priority Claimed::  
Foreign Application Three::  
Filing Date::  
Country::  
Priority Claimed::

#### **Assignee Information**

Name of assignee:: ANELVA CORPORATION  
Assignee Address Line One:: 8-1, Yotsuya 5-chome,  
Assignee Address Line Two::  
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